IN	TRODUCTION TO MIC	ROEL	ECTROMECHANICAL SYSTEMS								
1	Course Title:	INTRODUCTION TO MICROELECTROMECHANICAL SYSTEMS									
2	Course Code:	EEM4503									
3	Type of Course:	Optional									
4	Level of Course:	First Cyc	le								
5	Year of Study:	4									
6	Semester:	7									
7	ECTS Credits Allocated:	4.00									
8	Theoretical (hour/week):	3.00									
9	Practice (hour/week):	0.00									
10	Laboratory (hour/week):	0									
11	Prerequisites:	None									
12	Language:	Turkish									
13	Mode of Delivery:	Face to face									
14	Course Coordinator:	Doç. Dr. ESİN KARPAT									
15	Course Lecturers:	Yok									
16	Contact information of the Course Coordinator:	Dr. Öğr. Üye. Esin KARPAT Mühendislik Fakültesi Elektrik-Elektronik Mühendisliği Bölümü Ofis:320 0.224.294 20 20									
17	Website:										
18	Objective of the Course:	The aim of the lectures is to give an overview of the Microelectromechanic systems world and the MEMS devices. It has been structured so to introduce the main features and properties of Microelectromechanical systems and their current and potential advantages which mainly derive from miniaturization and the evolution of the standard IC technological approach.									
19	Contribution of the Course to Professional Development:	They gain the knowledge about the material technology of the new age and the designs of micro-sized sensors, robots and devices of the future.									
20	Learning Outcomes:										
	•	1	To be able to gain an interdisciplinary overview of the current state of MEMS								
		2	To be able to learn microfabrication methods								
		3	To be able to learn different applications of MEMS								
		4									
		5									
		6									
		7									
		8									
		9									
		10									
21	Course Content:	• 									
		Course Content:									
Week	Theoretical		Practice								
1	Introduction to MEMS.										

କ୍ଷିଶନ୍ଦି I Cred	it of t	ne Co		n Tec	hnique	s Use	d in th	e Me the	e pricip	les of l		ludag l	Jnivers	sity Ass	4.00 4.00 accordin		
sðr Fl	828/		urse					10	0.00						4.00		
sðr Fl	828/		urse												4.00		
		30 hr															
VUIK	Load														120100		
Total Work Load															120.00		
Exam	s					2		10	0.00			6.00		6.00			
hers									0.00					0.00			
								0.0	00 2.0						2.00		
									0				0.00			0.00	
						1		4α	10000				0.00			0.00	
<u>. </u>	منسب	AOT	(17150					`	1 4							42.00	
		epera	tion						0 0.00								
		•								ing, ive		_	501110			<i>.</i> u,	
											to mich				Load (hour)		
			5						Numb	or		Dure	ation (hour)	Total V	Vork	
med	chanio	cal, et	c)			aı,		L									
			·	cal h	iologia	al											
MEI	MS de	evices	(Digit	al mio	cromirr	ors,											
			<u> </u>	caling)								_			_	
	-				onanio												
	App Mat Des Mer Mic Mic Mic Mic Mic Mic Mic Mic tes tes tes tes tes tes tes	Application Materials Design P Mems pro Mems pro Microfabo Microfabo Repeatin MEMS do acceleror Microsen mechanic MEMS A Future of tes Materials cals/Labs Materials cals/Labs Materials cals/Labs	Applications of Materials Design Principl Mems products Microfabricatio Microfabricatio Microfabricatio Repeating court MEMS devices accelerometers Microsensors (mechanical, etc MEMS Actuato Future of MEM Future of MEM tes Materials: cals/Labs Materials: cals/Labs Materials: cals/Labs Materials: cals/Labs Materials: cals/Labs Materials: cals/Labs	Applications of MEM Materials Design Principles (Set Mems products Microfabrication - But Microfabrication - Microfabrication - Microfabrication - Microfabrication MEMS devices (Digital accelerometers, etc) MEMS devices (Digital accelerometers, etc) Microsensors (chemimechanical, etc) MEMS Actuators. Future of MEMS tes Materials: cals/Labs Materials: cals/Labs	Applications of MEMS Applications of MEMS Materials Design Principles (Scaling Mems products Microfabrication - Bulk Microfabrication - Bulk Microfabrication - Micro surf Repeating courses MEMS devices (Digital microcelerometers, etc) Microsensors (chemical, brechanical, etc) MEMS Actuators. Future of MEMS tes Materials: cals/Labs Materials: cals/Labs Materials: cals/Labs Materials: cals/Labs Morkapheject	Materials Materials Design Principles (Scaling) Mems products Microfabrication - Bulk Microfabrication-Micro surface Repeating courses MEMS devices (Digital micromirrace) MEMS devices (Digital micromirrace) MEMS devices (Digital micromirrace) MEMS Actuators. Future of MEMS tes Memory of MEMS tes Materials: cals/Labs Morkeone of antion of a state of	Applications of MEMS Applications of MEMS Materials Design Principles (Scaling) Mems products Microfabrication - Bulk Microfabrication-Micro surface Repeating courses MEMS devices (Digital micromirrors, accelerometers, etc) Microsensors (chemical, biological, mechanical, etc) MEMS Actuators. Future of MEMS tes Materials: cals/Labs Assessment Assessment Morks morks Materials: cals/Labs Assessment Assessment Assessment Assessment Materials: cals/Labs Assessment Morks morks morks Materials: cals/Labs Assessment Assessment Morks Morks Morks Morks Morks	Applications of MEMS Materials Design Principles (Scaling) Mems products Microfabrication - Bulk Microfabrication - Micro surface Repeating courses MEMS devices (Digital micromirrors, accelerometers, etc) Microsensors (chemical, biological, mechanical, etc) MEMS Actuators. Future of MEMS tes Meterials: aals/Labs Assessment Materials: aals/Labs Materials: Materials: aals/Labs Materials Materials <td>Materials Image: state of the state o</td> <td>Applications of MEMS Image: Second State Sta</td> <td>Applications of MEMS Image: Second State Sta</td> <td>Applications of MEMS Materials Design Principles (Scaling) Mems products Microfabrication - Bulk Microfabrication - Bulk Microfabrication - Micro surface Repeating courses MEMS devices (Digital micromirrors, accelerometers, etc) Microsensors (chemical, biological, mechanical, etc) MEMS Actuators. Future of MEMS Ites Number VigNetrials: actuators. Future of MEMS Ites Number VigNetrials: als/Labs 0 VigNetrials: 1 Materials: als/Labs 0 VigNetrials: 1 Materials: als/Labs 0 VigNetrials: 1 Materials: 0 VigNetrials: 0 VigNetrials: 0 VigNetrials: 0 VigNetrials:</td> <td>Materials Image: state of the state o</td> <td>Applications of MEMS Image: Second Secon</td> <td>Applications of MEMS Image: Second State Sta</td> <td>Applications of MEMS Image: Second Stress Stres</td>	Materials Image: state of the state o	Applications of MEMS Image: Second State Sta	Applications of MEMS Image: Second State Sta	Applications of MEMS Materials Design Principles (Scaling) Mems products Microfabrication - Bulk Microfabrication - Bulk Microfabrication - Micro surface Repeating courses MEMS devices (Digital micromirrors, accelerometers, etc) Microsensors (chemical, biological, mechanical, etc) MEMS Actuators. Future of MEMS Ites Number VigNetrials: actuators. Future of MEMS Ites Number VigNetrials: als/Labs 0 VigNetrials: 1 Materials: als/Labs 0 VigNetrials: 1 Materials: als/Labs 0 VigNetrials: 1 Materials: 0 VigNetrials: 0 VigNetrials: 0 VigNetrials: 0 VigNetrials:	Materials Image: state of the state o	Applications of MEMS Image: Second Secon	Applications of MEMS Image: Second State Sta	Applications of MEMS Image: Second Stress Stres	

ÖK2

ÖK3	0	0	1	0	0	0	0	0	0	0	0	0	0	0	0	0	
LO: Learning Objectives PQ: Program Qualifications																	
Contrib ution Level:	ution				2 low			3 Medium			4 High			5 Very High			